

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

Confirmation No.: 2933

Hiroyuki ARAKI et al.

Date: June 19, 2007

Serial No.: 10/730,465

Group Art Unit: 1746

Filed: December 8, 2003

Examiner: Michail Kornakov

For: SUBSTRATE TREATING APPARATUS AND SUBSTRATE TREATING METHOD

VIA EFS-WEB

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

SUBMISSION

Sir:

Submitted herewith is a copy of a search report issued by a patent searching authority other than the PTO and the cited art together with a form listing the same for the convenience of the Examiner.

I certify that each item of information contained in this Submission was cited in a communication from a foreign patent office in a counterpart foreign application and that this communication was not received by any individual designated in 37 C.F.R. 1.56(c) more than 30 days prior to the filing of this Submission.

THIS CORRESPONDENCE IS BEING
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Respectfully submitted,



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APPLICANT'S ART CITATION (Use several sheets if necessary)		Application 10/730,465		OFGS File No. P/1596-71			
		Applicant Hiroyuki ARAKI et al.					
		Filing Date December 8, 2003		Group Art Unit 1746			
U.S. PATENT DOCUMENTS (not submitted for applications filed after 6/30/03)							
Examiner Initial	Document Number	Date MM-YYYY	Name	Class	Sub- class	Filing Date If Appropriate	
	US-						
	US-						
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FOREIGN PATENT DOCUMENTS							
	Document Number	Date MM-YYYY	Country	Class	Sub- class	Translation	
						Yes	No
	06-252117	09-1994	Japan			X	
	10-177979	06-1998	Japan			X	
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)							
		Office Action dated May 22, 2007 for Japanese Patent Application No. JP2002-359357					
Examiner		Date Considered					
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609, Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.							